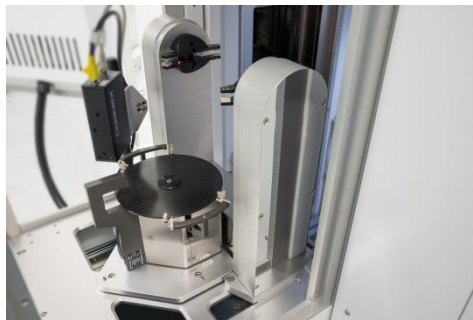
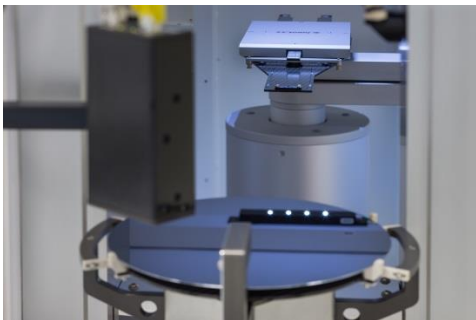




The InnoLas **Wafer Sorting System IL C3200** for
the flexible & fast sorting of your wafers



Handling System

Wafer Sizes	300 mm
Wafer Transfer	Single Arm Robot – Double End Effector
Wafer Alignment	Opto-mechanical
Wafer Handling	Vacuum / Edge Grip (optional)
Loading Stations	Up to 3
Cassette Loading	AGV / PGV / OHT
Throughput Sorting (wafers/hr)	250
Throughput Transfer (wafers/hr)	380

Reading System

Readable Fonts	Dot Matrix	SEMI OCR 5x9 / 10x18 / 15x27
	Barcode	SEMI BC 412, IBM BC412
	2D Code	SEMI T7, ECC200
	Engraved Mode	
Checksum	SEMI / IBM / customized (optional)	

Sorting

Types	Wafer ID / Wafer Weight & Thickness (optional)
Modes (ID)	Sort (ascending, descending & random)
	Split (even, uneven, random)
	Merge
Modes (Weight / Thickness)	Sort (ascending, descending & random)

Facility Requirements

Electrical	230 V (1P/1N/1PE) / 60 Hz / 16 Amps Optional: 115-200-240-370-380-400-420-480V
Power Consumption	1050 W
Communication	Ethernet RJ45 (SECS/GEM optional)
Vacuum	-800 mbar / 8mm OD connection
Exhaust	n/a
CDA – Compressed Dry Air	6 bar / 8mm OD connection
PFO – Process Fluid Outlet	8mm OD connection
Weight	500 kg
Dimension (w x l x h)	1879 x 2947 x 2270 mm

General

System Frame	Stainless Steel
System Panels	Powder coated
Mini Environment	ISO 3 (ISO 14644-1) / Class 1 (US FED STD 209E)
Certification	CDRH #0010530 / CE